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Docket No.: M4065.0018/P018-A
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Rodney C. Langley, et al

Application No.: 09/507,465

Group Art Unit: 1765

Filed: February 22, 2000

Examiner: M. Anderson

For: METHOD AND APPARATUS FOR
PLASMA ETCHING A WAFER

REQUEST FOR ACKNOWLEDGEMENT OF INFORMATION DISCLOSURE
STATEMENT

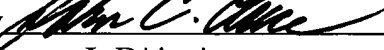
Commissioner for Patents
Washington, DC 20231

Dear Sir:

It is respectfully requested that the Information Disclosure Statement filed June 14, 2000, be acknowledged by the Examiner in charge of this application. Specifically, the Examiner is requested to initial and return the Information Disclosure Citation appended to the Information Disclosure Statement filed June 14, 2000.

Dated: March 10, 2003

Respectfully submitted,

By 
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